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# ***Optical System Alignment, Tolerancing, and Verification XI***

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Richard N. Youngworth**  
*Editors*

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## Introduction

The San Diego SPIE Optics and Photonics Symposium has provided a beautiful setting for a world-class conference for Optical System Alignment, Tolerancing, and Verification XI. As chairs of this conference, we are continually pleased with the technical content, authors, program committee, and SPIE. We find it difficult to express how thankful and humbled we are, by the community's and SPIE's support of a conference that embodies the traits of an international event. The 2017 conference had four sessions with excellent talks, in addition to some posters presented at the poster session. Of special note is that all presenters successfully submitted proceedings papers, for a total of 21 in the volume. Having 100% manuscript submission is excellent and this provides the community at large the technical content of the conference.

This year there were many highlights in the conference and we encourage the community to peruse the proceedings. We had a high value first session covering papers in alignment and verification topics. The second session involved a strong set of papers primarily covering tolerancing of optical systems, including coverage of two key international standards in the ISO 10110 drawing series. The sessions in the afternoon were both excellent, with papers on aligning optical systems, entailing not just alignment of specific systems but also methodology and hardware for aligning optical systems. The invited paper on Zernike polynomials and alignment was valuable, especially as it is useful to different fields including visual optics. The poster session was well attended and covered alignment of optical systems.

This conference will continue in 2018. We encourage everyone interested in optical system alignment, tolerancing, and verification to look for the call for papers and submit their work early 2018. Please feel free to contact us, or anyone in our program committee, for questions, requests or comments.

See you in San Diego in August 2018.

**José Sasián**  
**Richard N. Youngworth**

